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IN THE UNITED STATES
PATENT AND TRADEMARK OFFICE

In re Patent Application of:

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|-------------------|---|-------------------------|------------------|
| Inventor: | Monroe et al | Confirmation No: | 9548 |
| Serial No. | 10/677,539 | Examiner: | Mai Huong C Tran |
| Filed: | Oct 02, 2003 | Group Art Unit: | 2818 |
| Title: | MEMS Device And Method Of Forming MEMS Device | | |

Commissioner for Patents
P O BOX 1450
Alexandria VA 22313-1450

RESPONSE TO RESTRICTION REQUIREMENT

In response to your Office Action/Restriction Requirement dated September 21, 2004; Applicants affirm the election of Group II (Claims 1-27) without traverse.

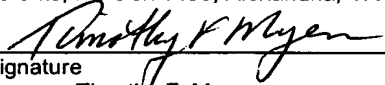
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Respectfully submitted,

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I hereby certify that this correspondence is being deposited on the date indicated below with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, PO Box 1450, Alexandria, VA 22313.


Signature
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9/29/04
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